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CCS L50



**NATIONAL STANDARD OF THE
PEOPLE'S REPUBLIC OF CHINA**

GB/T 48096-2026

**Laser Doppler measurement method for dynamic displacement
parameters of micro-electromechanical structures**

微机电结构动态位移参数的激光多普勒测量方法

(English Translation)

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Foreword

GB/T 48096-2026 is a recommended national standard (GB/T) of the People's Republic of China, issued on 28 August 2026 by the State Administration for Market Regulation and the Standardization Administration of China, with effect from 1 March 2027.

It is under the responsibility of the Chinese Academy of Sciences.

Classification: ICS 17.180.99; CCS L50.

1 Scope

This standard describes a laser Doppler measurement method for dynamic displacement parameters of micro-electromechanical structures. Micro-electromechanical devices, often called MEMS, include sensors and actuators with very small moving parts, and measuring their motion calls for non-contact optical techniques. The document is intended for MEMS designers, foundries, metrology laboratories and researchers who characterize device behavior.

It takes effect on 1 March 2027, with the Chinese Academy of Sciences as the responsible body. It is a recommended national standard (GB/T), so its use is voluntary unless required by agreement. A shared national method helps manufacturers and customers compare measured displacement results and supports consistent reporting between labs. It is a newly issued method. Teams developing inertial sensors, resonators, micro mirrors or similar structures may find the method relevant when documenting dynamic performance.